

To: Facsimile Number: 703-746-9179

Total Pages Sent 2

From:

Texas Instruments Incorporated
Facsimile: 972-917-4418

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Applicant Hiroaki Niimi, et al.

Docket Number: TI-32705

Serial No.: 09/885,744

Art Unit: 2823

Filed: 06/20/01

Examiner: Khiem D. Nguyen

For: Method for Annealing Ultra-Thin, High Quality Gate Oxide
Layers Using Oxidizer/Hydrogen Mixtures

CERTIFICATION OF FACSIMILE TRANSMISSION

I hereby certify that the following papers are being transmitted by facsimile
to the U.S. Patent and Trademark Office on the date shown below:Karen Vertz
Karen Vertz11-19-03
Date

FACSIMILE COVER SHEET

<input checked="" type="checkbox"/> FACSIMILE COVER SHEET <input type="checkbox"/> NEW APPLICATION <input type="checkbox"/> DECLARATION <input type="checkbox"/> ASSIGNMENT <input type="checkbox"/> FORMAL DRAWINGS <input type="checkbox"/> INFORMAL DRAWINGS <input type="checkbox"/> CONTINUATION APPN (# Pages) <input type="checkbox"/> DIVISIONAL APPN		<input type="checkbox"/> AMENDMENT (# Pages) <input type="checkbox"/> EOT <input checked="" type="checkbox"/> NOTICE OF APPEAL <input type="checkbox"/> APPEAL (# Pages) <input type="checkbox"/> ISSUE FEE & PUBLICATION FEE (1 Page) <input type="checkbox"/> REPLY BRIEF (IN TRIPLICATE) (# Pages) <input type="checkbox"/> ELECTION
NAME OF INVENTOR(S): Hiroaki Niimi et al. TITLE OF INVENTION: Method for Annealing Ultra-Thin, High Quality Gate Oxide Layers Using Oxidizer/Hydrogen Mixtures		RECEIPT DATE & SERIAL NO.: Serial No.: 09/885,744 Filing Date: 06/20/01
TITLE NO.: TI-32705	DEPOSIT ACCT. NO.: 20-0668	
FAXED: 11-19-03 DUE: 11-19-03 ATTY/SECY: GCH/kjv		

This facsimile is intended only for the use of the address named and contains legally privileged and/or confidential information. If you are not the intended recipient of this telecopy, you are hereby notified that any dissemination, distribution, copying or use of this communication is strictly prohibited. Applicable privileges are not waived by virtue of the document having been transmitted by Facsimile. Any misdirected facsimiles should be returned to the sender by mail at the address indicated on the cover sheet.

Texas Instruments Incorporated
PO Box 655474, M/S 3699
Dallas, TX 75265-5474

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

TI-32705

Hiroaki Niimi, et al.

Examiner: Khiem D. Nguyen

Serial No.: 09/885,744

Art Unit: 2823

Filed: 06/20/01

For: Method for Annealing Ultra-Thin, High Quality Gate Oxide Layers Using Oxidizer/Hydrogen Mixtures

NOTICE OF APPEAL FROM THE PRIMARY EXAMINER TO THE BOARD OF APPEALS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATION OF FACSIMILE TRANSMISSION
I hereby certify that the following papers are being transmitted by
facsimile to the U.S. Patent and Trademark Office at 703-746-9179
on the date shown below:

Sir:

Karen Vertz
Karen Vertz

11-19-03
Date

Applicants hereby appeal to the Board of Appeals from the decision dated August 19, 2003 of the Primary Examiner finally
rejecting claims 1-7 and 9-13.

The item(s) checked below are appropriate:

1. ☐ An extension of time to respond to the final rejection

☐ was granted on ☐.

☐ is requested for ☐ month(s).

2. ☐ A timely response to the final rejection has been filed, as provided in 841 O.G. 1411.

3. ☒ Fee \$330.00:

☐ Not required (Fee paid in prior appeal)

☒ The Commissioner of Patents is hereby authorized to charge any fees which may be required, or credit any overpayment to Deposit Account No. 20-0668 of Texas Instruments Incorporated. **This form is submitted in triplicate.**

Signature [Rule 191(b)]

Post Office Address (to which correspondence is to be sent)
Texas Instruments Incorporated
P.O. Box 655474, MS 3999
Dallas, TX 75265
(972) 470-0130

Gary C. Honeycutt
Gary C. Honeycutt
Reg. No. 20,250
Attorney for Appellants